



B/ITW

In re the Application of: **OZAKI, Takashi, et al.**

Group Art Unit: **2813**

Serial No.: **10/517,765**

Examiner: **MCCALL SHEPARD, Sony**

Filed: **February 3, 2006**

P.T.O. Confirmation No.: **6791**

FOR: **SUBSTRATE TREATING APPARATUS AND METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE**

**AMENDMENT AFTER ALLOWANCE UNDER 37 C.F.R. 1.312**

**MAIL STOP AF**

OK TO ENTER: /S.M.S./

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

April 13, 2010

Sir:

Applicants received a Notice of Allowance dated **January 28, 2010** in connection with the above-identified application. It is respectfully requested that the following amendment be made to the claims of this application:

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 6 of this paper.